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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/905,286
Filing Date July 13, 2001
Inventor Cem Basceri et al.
Assignee Micron Technology, Inc.
Group Art Unit 1762
Examiner Fuller, Eric B.
Attorney's Docket No. MI22-1724
Title: Chemical Vapor Deposition Methods of Forming Barium Strontium Titanate
Comprising Dielectric Layers

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - - See attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

This Supplemental Information Disclosure Statement is being filed after the filing of the Request for Continued Examination (RCE) Application and before receipt of the first Office Action. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. §1.17(p) to Deposit Account No. 23-0925. Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

Citation of these references is respectfully requested.

Respectfully submitted,

Date: June 11, 2003

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LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Cem Basceri et al.FILING DATE
July 13, 2001GROUP
1762

U.S. PATENT DOCUMENTS

Examiner (Initials)	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
AA	6,337,496 B2	01-2002	Jung			
AB	6,507,060 B2	01-2003	Ren et al.			
AC						
AD						
AE						
AF						
AG						
AH						
AI						
AJ						
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FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
AM							
AN							
AO							
AP							
AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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AS		
AT		

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.